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(56) References cited:

GB-A- 2 421 115

- **JUNG HO ET AL: "Lift-off process using bilayer ultraviolet nanoimprint lithography and methacryloxypropyl-terminated-polydimethyl siloxane-based imprint resin", JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY: PART B, AVS / AIP, MELVILLE, NEW YORK, NY, US, vol. 27, no. 4, 24 June 2009 (2009-06-24), pages 1861-1864, XP012129400, ISSN: 1071-1023, DOI: 10.1116/1.3156739**
- **CARLBERG P ET AL: "Lift-off process for nanoimprint lithography", MICROELECTRONIC ENGINEERING, ELSEVIER PUBLISHERS BV., AMSTERDAM, NL, vol. 67-68, 1 June 2003 (2003-06-01), pages 203-207, XP004428870, ISSN: 0167-9317, DOI: 10.1016/S0167-9317(03)00072-8**
- **AUSTIN MICHAEL D ET AL: "Fabrication of 70 nm channel length polymer organic thin-film transistors using nanoimprint lithography", APPLIED PHYSICS LETTERS, AIP, AMERICAN INSTITUTE OF PHYSICS, MELVILLE, NY, US, vol. 81, no. 23, 2 December 2002 (2002-12-02), pages 4431-4433, XP012032713, ISSN: 0003-6951, DOI: 10.1063/1.1526457**

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- **PANNEMANN C ET AL: "Nanometer scale organic thin film transistors with Pentacene", MICROELECTRONIC ENGINEERING, ELSEVIER PUBLISHERS BV., AMSTERDAM, NL, vol. 67-68, 1 June 2003 (2003-06-01), pages 845-852, XP004428959, ISSN: 0167-9317, DOI: 10.1016/S0167-9317(03)00146-1**